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**INFORMATION DISCLOSURE CITATION**  
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Masahiko Ishida et al.Filing Date  
March 22, 2006Group Art Unit  
unknown**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

**U.S. PATENT APPLICATION PUBLICATIONS**

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**FOREIGN PATENT DOCUMENTS**

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
/M.H./		2003-238123	08.27.2003	NEC CORP. JPX	Int. Cl		<input checked="" type="checkbox"/>	
/M.H./		2003-017508	17.01.2003	NEC CORP. JPX	Int. Cl		<input checked="" type="checkbox"/>	

**OTHER DOCUMENTS** *(Including Author, Title, Date, Pertinent Pages, Etc.)*

/M.H./		J. Fujita et al. Graphitization of Fe-doped amorphous carbon pillars grown by focused-ion-beam-induced chemical-vapor deposition, Journal of Vacuum Science & Technology B, second series, volume 20, number 6, 11/2002; pages 2686-2689
/M.H./		Yoshikazu Homma et al. Growth of suspended carbon nanotube networks on 100-nm-scale silicon pillars; Applied Physics Letters, volume 81, number 12; 09.16.2002; pages 2261-2263

EXAMINER	/Michelle Hou/	DATE CONSIDERED	12/23/2008
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.